SEMICONDUCTOR TECHNOLOGY RESEARCH, INC.

Virtual Reactor

Software for Modeling of Long-Term Growth of Wide-Bandgap Crystals





STR Virtual Reactor (VR) is a family of standalone 2D software tools designed for the simulation of long-term growth of bulk crystals from the vapor phase

Virtual Reactor editions:

- Physical Vapor Transport
 - For growth of SiC crystals: VR-PVT SiC[™]
 - For growth of AIN crystals: VR-PVT AIN™

• Hydride Vapor Phase Epitaxy

• For growth of GaN crystals: HEpiGaNS[™] (Hydride Epitaxial GaN Simulator)

Chemical Vapor Deposition

• For growth of SiC crystals: VR-CVD SiC[™]



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Ferdinand-Braun-Institut für Höchstfrequenztechnik

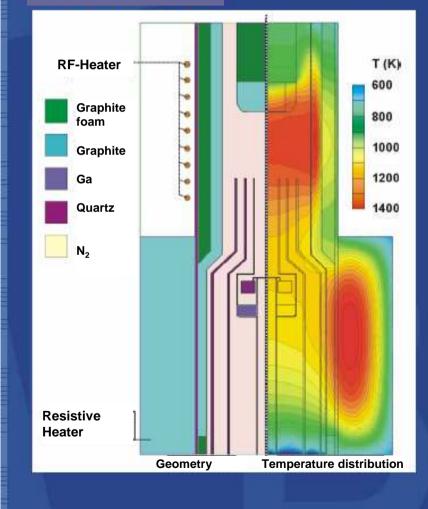
Fabrication of thick 2-inch layers by HVPE in vertical reactor: growth process optimization

> S. Hagedorn, E. Richter, U. Zeimer, M. Weyers, G. Tränkle

translating ideas into innovation

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Simulation



HEpiGaNS (STR)

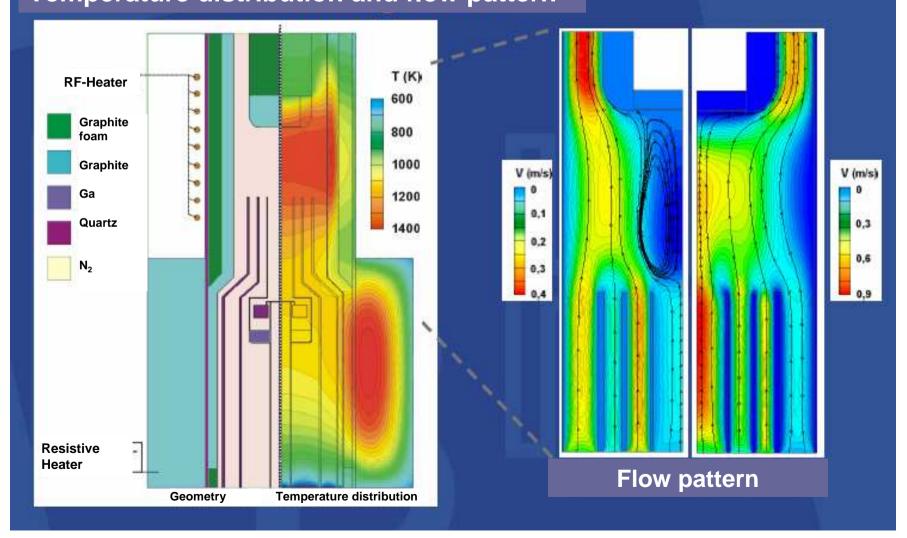
Heat Transfer
Gas flow and species mass transport
Quasi-thermodynamic model of heterogeneous chemical processes

> Temperature

- Flow pattern
- Species partial pressures
- > GaN growth rate
- ≻ V/III ratio



Temperature distribution and flow pattern



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Comparison of numerical predictions with experimental data

